

Line Number	Hits	Search Text	DB	Time stamp
-	10	(LPD or light near3 point near3 defect and epitax\$4 near3 wafer) and nitrogen and 117/\$4.cccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/01/27 13:28
-	44	(LPD or light near3 point near3 defect same epitax\$4 near3 wafer and defect near4 free same (epitax\$4 near3 (film or layer))) and 117/\$4.cccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/01/27 13:49
-	19	(LPD or light near3 point near3 defect) same epitax\$4	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/01/27 14:15
-	58	(LPD or light near3 point near3 defect) same (cop or crystal near4 particle)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/01/27 14:25
-	39	(LPD or light near3 point near3 defect) and epitax\$4 near3 wafer	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/01/27 14:29
-	60	(denud\$3 or dz) same epitax\$4 and (silicon near4 wafer)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/01/27 15:28
-	19	((denud\$3 or dz) same epitax\$4 and (silicon near4 wafer)) and defect near1 free	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/01/27 15:39
-	27	SUMITOMO.as. and epitax\$4 near3 wafer and dop\$3 near4 nitrogen	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2003/01/28 14:15